

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2067	SERIAL NO. 15/624340 <small>Filed-Monday</small>		
LIST OF ART CITED BY APPLICANT <small>(Use several sheets if necessary)</small>				APPLICANT Brant A. McClure et al			
				FILING DATE Filed Herewith	GROUP Unknown 2831		
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
<div style="font-size: 2em;">↓</div>	AA	6,180,481	1/01	DeBoer et al			
	AB	6,218,256	4/01	Agarwal			
	AC	6,204,049	8/00	Soleyappan			
	AD	6,180,447	1/01	Park			
	AE	6,274,428	8/01	Wu			
	AF	6,124,158	9/00	Dautartas et al			
	AG	6,144,060	11/00	Park			
	AH	5,316,982	5/94	Taniguchi			
	AI	6,281,142	8/99	Bacari et al			
	AJ	6,204,172	9/98	Marah			
	AK	5,432,732	7/95	Ohmi			
	AL	6,242,299	06/01	Hickert			
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
<div style="font-size: 2em;">↓</div>	AR	A.W. Ott, et al., "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pps. 128-136.					
	AS						
EXAMINER				DATE CONSIDERED			
/Nguyen Ha/				06/20/2007			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

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